A Software Package for Numerical Simulation of Semiconductor Devices under HPM Environment

Author: Gong Ding Supervisor: Wang Jianguo Background Theory of Semiconductor Physics The Numerical Methods in **Semiconductor Device Simulation** GSS, A General-purpose Semiconductor Simulator Further Works

HPM Weapons





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- Annual and development probability and so all and second to realistic minimum probability of an all Micro-Research.
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RANETS-E (Russia)

E-BOMB(US)



Various ways of incident HPM wave coupling to an electronic system

HPM energy flows into transistors

Printed Circuit Board



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dB uA/m Ē 180 × Chip X, mm

Because the characteristic length of semiconductor device is relatively smaller than the wavelength of HPM, the energy deposit can be neglected.

Unfortunately, PCB wires are efficient antennas which can receive HPM energy.

In this thesis, transistors only stimulated by current or voltage sources come from chip pins.

Part2 Semiconductor Physics

S. M. Sze, *Physics of Semiconductor Devices*, 2nd ed. (New York: John Wiley & Sons, 1981).

 Band structure
 Fermi-Dirac distribution
 Classical Boltzmann Transport Equation

Part3 Numerical Methods

Governing Equations
Finite Volume Method
Discretization
Boundary Conditions
Nonlinear Solvers
Linear Solvers

Governing equations of HDM We only present equations for electrons here $\frac{\partial n}{\partial t} + \nabla \cdot (n\vec{\mathbf{v}}) = -R$ $\frac{\partial (m^* n \vec{v})}{\partial t} + \nabla \cdot (m^* n \vec{v} \vec{v}) + \nabla (nkT) = -en\vec{E} - \frac{m^* n \vec{v}}{\tau}$ \mathcal{T}_{p} $\frac{\partial(nw)}{\partial t} + \nabla \cdot (n\vec{v}w) + \nabla \cdot (nkT\vec{v}) = -en\vec{v} \cdot \vec{E} - \frac{nw - 2/3nkT_L}{\tau}$ $abla^2 \varphi = -rac{
ho}{arepsilon}$ If we simplify HDM, just drop energy equation and the first two items of moment equation, that is DDM.

Conservation form

The governing equations can be present in conservation form.

 $\frac{\partial \mathbf{Q}}{\partial t} + \frac{\partial \mathbf{F}_i}{\partial x_i} = \mathbf{S} \cdot \mathbf{Q}$ $n \mathbf{\bar{v}}$ n $m^* n \vec{\mathbf{v}} \vec{\mathbf{v}} + nkT$ $nw \vec{\mathbf{v}} + nkT \vec{\mathbf{v}}$ $\nabla \varphi$ $m^*n\vec{\mathbf{v}}$ $\mathbf{F} =$ nw 0 $\mathbf{S} \cdot \mathbf{Q}$ is the source item

Finite Volume Method

Use Gauss's law, the integration of the partial item over the control volume can be replaced by boundary integration. That is



 $\frac{\partial}{\partial t} \int \mathbf{Q} dV + \oint \mathbf{F}_i \cdot d\mathbf{s} = \int \mathbf{S} \cdot \mathbf{Q} dV$ Or the semi-discrete form: $\frac{d \overline{\mathbf{Q}}}{dt} V_{cell} + \sum \mathbf{F}_i \cdot l = \overline{\mathbf{S}} \cdot \overline{\mathbf{Q}} V_{cell}$ $\overline{\mathbf{Q}} \ \overline{\mathbf{S}} \text{ is the average value of the cell.}$

Discretization

How to get the flux at the boundary of cell is the key problem of FVM. A good HD scheme must satisfy high resolution, nonoscillation and total variation diminishing. In modern CFD world, least-squares reconstruction with limiters, flux upwindsplit and dual-time implicit stepping methods are widely used. Each of them has an uncountable number of papers.

Boundary Conditions

Ohmic BC
Schottky BC
Gate Contact of MOS Structure
*Current Boundary Condition

Current Boundary Conditions

The Newton's method fails to get convergence at the breakdown region if voltage boundary condition is used.



Therefore, current BC must be applied to satisfy the requirement of HPM simulation.

Nonlinear Solvers

The key process of semiconductor simulation is how to solve the large scale, nonlinear equations arising from discretization step. A flexible, stable and fast arithmetic must be implemented.

Basic Newton
Line Search
Trust Region

Newton's Method

f(x) = 0



Fast arithmetic: quadratic convergence But only convergence when $x \rightarrow x^*$ Only used in IV curve tracing or transient simulation.

Line Search

$$\mathbf{J}_k \delta_k = -f(x_k)$$
$$x_{k+1} = x_k + \alpha \delta_k$$

The first equation only determine the descent direction. Then the step size alpha is solved by a safeguarded polynomial interpolation of f(x).

This arithmetic only holds when Jacobian matrix is exact or nearly exact. GSS tried its best to get exact Jacobian matrix, so line search is the default nonlinear solver for get a initial solution.

Trust Region

$\mathbf{B}_k = \mathbf{J}_k + \lambda \mathbf{I}$

This method uses positive definite matrix B instead of J to reduce the step size. A sufficient small step size may satisfy toyler series and get convergent gradually.

Early edition of GSS didn't have exact Jacobian matrix, trust region was applicable. But now, line search method is recommended.

Linear Solvers

All the Nonlinear solvers request a fast linear solver. In most of the situation, an approximate linear solver is enough.

 LU Factorization Method
 Fixed Iterative Method (GS,SOR,SSOR)
 Krylov Subspace Method (CG,GMRES,BICG)

Part4 Introductions of GSS

Pre-processor
Model File Format
Command File Syntax
Flexible Material Database
Build-in Solvers
Post-processor



What is GSS?

GSS is a General-purpose Semiconductor Simulator. Besides several libraries, version 0.42 has more than 20000 lines of c++ code.

GSS 0.42 have these features

- Use CGNS as standard input/output file format
- Run time parameters are specified by cmd file
- Unstructured mesh(triangle/rectangle) support
- Adaptive mesh refinement
- Two build-in solvers : DDM and HDM

Software Structure of GSS



Pre-Processor

GSS support Medici compatible model description language, which can build device model, do mesh division and adaptive mesh refinement easily. Beside that, some auxiliary tools can be used as pre-processor.

SGrid: Another Pre/Post Processor



Ortho_ComputeViewport

Interface to Other Software

GSS can employ Sgframework or Medici to generate device description file. While a small tool TIFTOOL can convert Medici TIF file to CGNS file, which can be read by GSS.

CGNS, The I/O File Format **CGNS: CFD General Notation System** Supported by NASA and many commotional **CFD** Corporations. Mesh, boundary condition and solution data are stored in one file. Freeware Adfviewer and Cgnsplot can help for debugging. CGNS is well supported by ICEM CFD10.0, the world's top pre/post processor.

View CGNS file

<pre>@ADFviewer : mos_sg.cgns</pre>		<u> </u>			
<u>File Config Tree Tools U</u> tilities <u>H</u> elp					
Node Tree Node Description					
	Parent Node				
CGNSLibraryVersion	Node Name	*			
	Node Label				
🖕 🔁 SiO2					
- 🖹 ZoneType	Link Description				
- 🖹 RegionType	Link File Br	rowse			
		owse			
	Data Description				
	Data Tura				
ZoneGridConnectivity	Disession	<u> </u>			
E- 🔁 ZoneBC	Dimensions				
📙 🖻 📴 Si	Bytes				
- 🖹 ZoneType	create modify read clear dr	elete			
RegionType		NOTO			
	Node Data				
	Line Values/Line				

Show Mesh



Mesh editor (by ICEM)





Post process (by ICEM)



{solution;potential}

0.5262
0.4679
0.4097
0.3514
0.2931
0.2349
0.1766
0.1183
0.06004
0.001775
-0.05650
-0.1148
-0.1730
-0.2313
-0.2896
-0.3478

Command file

At present, lex and yacc are used to parse command file. It contains:

- Various run time parameters
- Boundary condition
- Voltage source attached to BC

Solver specification

```
# common line
# All the command has the syntax: keyword parameter=string|double
# String must begin with character or underline.
# Character, digital, underline and dot are allowed in string.
# The length of string is limited to 30 characters.
# Numerical value double support c syntax float point number.
# The Unit in command file.:
# Time Unit:ps voltage Unit:V Freq Unit:THz Length Unit:cm
#______
# static command, in lower case
set MeshFile = mesh.cons # specify cons file which contains mesh,doping and boundary lable
set ModelFile = model.dat # specify physical model
set DeviceDepth = 0.01  # device depth in Z dimension. Unit:cm
set MeshScale = 1e-6 # the internal unit of length during the simulation. For DDM
                     # default value 1e-6cm is ok. For HDM 1e-4cm or 1e-5cm is more convenient.
  _____
# voltage source.
# ID can be specified by user, limited to 32 characters, c syntax.
# reference: voltage source in spice model
vsource Type = VDC ID = GND Tdelay=0 Vconst=0
vsource Type = VDC ID = VCC Tdelay=0 Vconst=5
vsource Type = VSIN ID = Vs Tdelay=1 Vamp=0.1 Freq=1e-6
vsource Type = VEXP ID = V1 Tdelay=0 TRC=1 TFD=3 TFC=1 Vlo=0 Vhi=1
vsource Type = VPULSE ID = V2 Tdelay=0 Tr=1 Tf=1 Pw=5 Pr=10 Vlo=0 Vhi=1
```

```
# specify boundary condition.
# ID must accord with the boundary name in cgns file
# electrode boundary
        OhmicContract|SchottkyContract|GateContract|InsulatorContract
#
# they have parameters of parasite res, cap and ind unit: Om, F, H
# SchottkyContract has an extra parameter, the barrier height.
# GateContract can specify the workfunc of gate electrode.
 InsulatorContract offers a simple way for describing Si/SiO2 interface,
#
        the Thick of oxide must be specified,
# NeumannBoundary has heat transfer rate parameter Kapa. unit ?
# InsulatorInterface is the interface of Si/SiO2, has a fixed charge density QF, unit ?
                                                  Res=0 Cap=0 Ind=0 Thick=1e-6 QF=0
boundary Type = InsulatorContract ID = SiSiO2
boundary Type = InsulatorInterface ID = IFACE
                                                  OF=0
boundary Type = GateContract
                                   ID = GATE
                                                   Res=0 Cap=0 Ind=0 WorkFunction=0
boundary Type = NeumannBoundary
                                   ID = WALL
                                                  Kapa=0
boundary Type = SchottkyContract ID = sqate
                                                 Res=0 Cap=0 Ind=0 Vbarrier=-0.8
boundary Type = OhmicContract
                                   ID = OMANODE Res=0 Cap=0 Ind=0
boundary Type = OhmicContract ID = OMCATHODE Res=0 Cap=0 Ind=0
boundary Type = OhmicContractID = OMSOURCERes=0Cap=0Ind=0boundary Type = OhmicContractID = OMDRAINRes=0Cap=0Ind=0
boundary Type = OhmicContract
                                                   Res=0 Cap=0 Ind=0
                                   ID = OMSUB
#FloatMetalGate may support later
```

```
# drive command, specify the solving process.
# keyword is in upper care
# reference: medici user's quide
# METHOD Type = DDM scheme = [Newton|Gummel] &
        SNES = [LineSearchCubic|LineSearchQuadratic|LineSearchNo|TrustRegion] &
       TStep = time number
# METHOD Type = HDM scheme = [Implicit|Explicit] FluxFunc = [AUSM|Roe] &
        Reconstruct = [FirstOrder|SecondOrder] CFL = cfl number
 ATTACH Electrode = electrode_name VApp = vsource_name
                        _____
# SOLVE Type = EOUILIBRIUM
# SOLVE Type = STEADYSTATE
# SOLVE Type = DCSWEEP VScan = electrode name IVRecord = electrode name &
       IVFile = file name VStart = v number VStep = v number VStop = v number
# SOLVE Type = TRANSIENT AUTOSAVE = time number IVRecord = electrode name &
       IVFile = file name TStart = time number TStop = time number
# MODELS not supported yet
# IMPORT CoreFile = file name
 EXTRACT CoreFile = file_name AscFile = file_name
# REFINE Variable = [Doping|Potential] Measure = [Linear|SignedLog] Dispersion = number
# PLOT Variable = Mesh Resolution=[Low|Middle|High] PSFile=file name
# PLOT Variable =[Na|Nd|ElecDensity|HoleDensity|Potential|EFieldX|EFieldy|Temperature]
        Resolution=[Low|Middle|High] PSFile=file name Measure=[Linear|SignedLog]
#
        AzAngle=angle number ElAngle=angle number Style=[Scale|Color|GrayLevel]
```

```
METHOD
                                                         #specify DDM method, this is the default solver.
         Tvpe = DDM
                     Scheme = Newton
                                       TStep=1e3
PLOT
        Variable=Mesh
REFINE
        Variable=Doping Measure=SignedLog Dispersion=1 #refine by doping
SOLVE
        Type=EQUILIBRIUM
                                                         #compute equilibrium state
        Variable=Potential Measure=Linear Dispersion=0.1 #refine by potential
REFINE
PLOT
        Variable=Mesh
SOLVE
        Tvpe=EOUILIBRIUM
                                                         #compute equilibrium state again
PLOT
        Variable=Na Resolution=Middle
                                         AzAngle=240 ElAngle=40 Style=Scale
PLOT
        Variable=Nd Resolution=Middle
                                         AzAngle=240 ElAngle=40 Style=Scale
        Variable=ElecDensity PSFile=electron Resolution=High AzAngle=240 ElAngle=40 Style=Color
PLOT
        Variable=HoleDensity PSFile=hole
                                             Resolution=High AzAngle=240 ElAngle=40 Style=Color
PLOT
PLOT
        Variable=Potential Resolution=High
                                                AzAngle=240 ElAngle=40 Style=GrayLevel
# extract mesh and solution
EXTRACT CoreFile=init.cgns
IMPORT
        CoreFile=init.cgns
                                              # import it
                                              # attach vsource to boundarv(electrode)
ATTACH
        Electrode=OMCATHODE VApp=GND
# DC sweep
SOLVE
        Type=DCSWEEP VScan=OMANODE IVRecord=OMANODE IVFile=iv.txt VStart=0 VStep=1e-2 VStop=1
#IMPORT CoreFile=break.cons
        Electrode=OMANODE
ATTACH
                             VApp=VCC
                                              VApp=Vs
# specify HDM method
METHOD
        Type=HDM
                             Scheme=Explicit FluxFunc=AUSM Reconstruct=FirstOrder CFL=0.1
SOLVE
        Type=TRANSIENT
                             AUTOSAVE=1
                                          TStart=0
                                                      TStop=10
METHOD
                             Scheme=Implicit FluxFunc=AUSM Reconstruct=SecondOrder CFL=2
        Tvpe=HDM
SOLVE
        Type=TRANSIENT
                             AUTOSAVE=1
                                          TStart=10
                                                       TStop=20
```

Graphic plot

- GSS requests Xwindow to do graphic plot.
- Support both 2D mesh displaying and 3D plotting of results.
- User can choose style, color and change view angle by mouse.
- In the future, Graphic user's interface will be built.

Solvers

The two popular methods in semiconductor simulation—DDM and HDM—are supported both.

 Use DDM method to get a zero bias solution is very fast and accurate while HDM needs a lot of time to get convergence.

HDM is suit for sub-micron device simulation such as MESFET and HEMPT

DDM Level 1

DDM is the basic method for

semiconductor simulation. It employs Newton's iterative method to solve nonlinear equations.

With the help of PETSC, the DDM solver is ready to go. Because PETSC support line search and trust region method, GSS can get convergence in most of the situation.

DDM Level 2

The thermal effects are critical when device attacked by HPM. Beyond the basic DDM solver, a lattice temperature corrected DDM solver (L2) is developed, which can simulate the thermal phenomena of devices.

Unfortunately, DDM L2 runs 2-10 times slower than original edition.



Original mesh

 autismum
 putteestist.)

 0.2844
 0.2854

 0.2875
 0.2795

 0.2879
 0.2879

 0.2879
 0.2879

 0.2879
 0.2879

 0.2879
 0.88523

 -0.89523
 -0.85923

 -0.89523
 -0.85924

 -0.3959
 -0.3149

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</tr



Potential distribution of equilibrium

Refined mesh





Temperature Distribution of forward bias



Frequent dependent simulation







Top left:1MHzTop right:100MHzBottom left:1GHz

Example 2 BJT circuit



Circuit scheme

Input file

advanced topic:we will compute transient reaction of a npn Transistor
<pre>#</pre>
voltage source and current source is needed here.
vsource Type = VDC ID = GND Tdelay=0 Vconst=0
vsource Type = VDC ID = VCC Tdelay=0 Vconst=3.0
vsource Type = VDC ID = Vb Tdelay=0 Vconst=0.7
vsource Type = VSIN ID = Vs
isource Type = IDC ID = Ib Tdelay=0 Iconst=0.002
isource Type = ISIN ID = Is Tdelay=0 Iamp=1e-5 Freq=1e6
#
specify boundary condition.
boundary Type = OhmicContact ID=Base Res=1000 Cap=1e-9 Ind=1e-6
boundary Type = OhmicContact ID=Emitter Res=0 Cap=0 Ind=0
boundary Type = OhmicContact ID=Collector Res=3000 Cap=0 Ind=0
import constiles are 2
METHOD Ture = DDML1 Scheme = Newton NS=LineSeerch LS=BCCS
ATTACH Flectrode=Collector Vann=VCC
ATTACH Electrode=Collector VApp=VCC
#ATTACH Electrode=Base VAnn=Vb VAnn=Vs # use voltage boundary condition.
ATTACH Electrode=Base Twne=Current LAnn=Th LAnn=Is # use current boundary condition.
SOLVE Type=STEADYSTATE # compute STEADYSTATE to get a initial value
METHOD Type = DDML1 Scheme = Newton NS=LineSearch LS=BCGS
SOLVE Type = TRANSIENT IVRecord=Collector IVRecord=Base \
IVFile=iv.txt TStart=0 TStep=1e-8 TStop = 2e-6

Result of Transient simulation



Example 3 multi-region NMOS

Here, a very complex NMOS transistor is simulated, which shows the multi-region processing capacity of GSS.

Mesh Structure



zone 1 lable : Drain 12 nodes 12 elements 23 voronoi edges zone 2 lable : Gate 26 nodes 24 elements 49 voronoi edges zone 3 lable : Oxide 146 nodes 200 elements 345 voronoi edges zone 4 lable : Silicon 797 nodes 1478 elements 2274 voronoi edges zone 5 lable : Source 12 nodes 12 elements 23 voronoi edges zone 6 lable : Substrate 22 nodes 20 elements 41 voronoi edges

Press ESC to continue





Example 3 multi-region NMOS



IV curve of Vgs=3V



At present, both explicit and implicit HDM method are ok. The Roe and AUSM schemes are supported.

 The HDM solver is consisted of two main parts: a Poisson solver and a CFD solver. Optimization of Poisson and CFD solver is a future project.

limitation of HDM

I did several tests with some transistors. The Numerical viscosity may cause terrible problems in bipolar transistor. HDM works well only with single carrier transistors such as MESFET and HEMT.

As a result, adaptive mesh refinement and second order reconstruction in space are done for anti-viscosity.

In the future, higher order Discrete Galerkin method may be introduced into GSS.

HDM example GaAs MESFET

Source	Gate	Drain
	Active layer	
	Buffer layer	

Result of MESFET



Electron density





Potential

IV curvy

HDM example NMOS Simplified NMOS Model. Na is set to zero. Only electron was considered.



Doping :Nd

Result of NMOS under Vds=5V, Vgs=5V



Potential

Future Works

- Build user-friendly Graphic User's Interface.
- support heterojunction device.
- Support optical mechanism.

*Support of FEM

For meeting the challenge of CCD simulation, GSS had introduced a background mesh, which enables using FEM to solve electromagnetic problems.



zone 1 lable : Air 1753 nodes 3173 elements 4926 voronoi edges zone 2 lable : Anode 22 nodes 20 elements 41 voronoi edges zone 3 lable : Cathode 62 nodes 60 elements 121 voronoi edges zone 4 lable : Si 1242 nodes 2353 elements 3594 voronoi edges

Press ESC to continue

A PN diode with background mesh

*Run GSS on a Cluster

 Since GSS support multi-region mesh, to write a parallel edition of GSS is not so difficult.

The nonlinear solver itself is well designed for cluster.

Special Thanks for Your Attention!

Presented by Gong Ding